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PTO/SB/04/10-01)  
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**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	<del>Unknown</del> 10/727889
Filing Date	<del>Even Date Herewith</del> 12/4/03
First Named Inventor	Iyer, Ravi
Group Art Unit	<del>Unknown</del> 2815
Examiner Name	Eckert II, George

Sheet 1 of 2

Attorney Docket No: 303.089US4

**US PATENT DOCUMENTS**

Examiner Initial *	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	Filing Date If Appropriate
JSL	US-4,872,947	10/10/1989	Wang, D.N., et al.	156	643	10/26/1988
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*JSL Eckert*

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Substitute Disclosure Statement Form (PTO-1449)

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Substitute for form 1449A/PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)	Complete if Known	
	Application Number	<del>Unknown</del> 10/727,889
	Filing Date	<del>Even Date Herewith</del> 12/4/03
	First Named Inventor	Iyer, Ravi
	Group Art Unit	<del>Unknown</del> 2815
	Examiner Name	Eckert II, George
Sheet 2 of 2		Attorney Docket No: 303.089US4

OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume+issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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*Jee Eshens*

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